



(19)

(11) Publication number:

02164017 A

Generated Document.

## PATENT ABSTRACTS OF JAPAN

(21) Application number: 63320281

(51) Intl. Cl.: H01L 21/02 B65G 43/00 H01L 21/027

(22) Application date: 19.12.88

(30) Priority:

(43) Date of application  
publication: 25.06.90(84) Designated  
contracting states:(71) Applicant: TOKYO ELECTRON LTD  
TERU KYUSHU KK

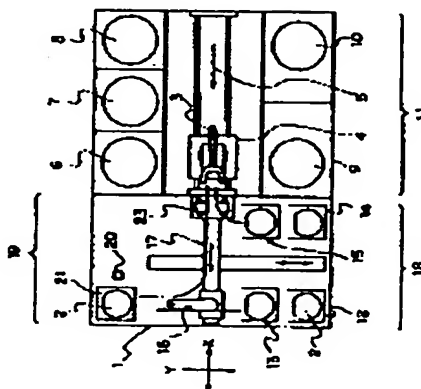
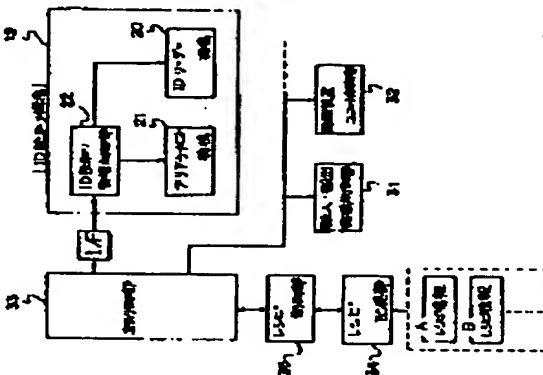
(72) Inventor: SAKAMOTO YASUHIRO

(74) Representative:

**(54) SEMICONDUCTOR  
MANUFACTURING  
APPARATUS****(57) Abstract:**

**PURPOSE:** To enhance production efficiency by a method wherein the contents of a process corresponding to the kind of article to be processed and a processing apparatus unit and a processing-workpiece transport mechanism are controlled on the basis of the contents of this process.

**CONSTITUTION:** An ID number on a semiconductor wafer 2 is read out by an ID number read-out mechanism. That ID information transmitted to a main control section 33 is transmitted to a recipe control section 35. Recipe information corresponding to this ID information is chosen from recipe information A, B, < stored in recipe storage section 34 by the recipe control section 35. That recipe information is transmitted to the main control section 35 again, and to a carry-in/carry-out mechanism 31 and a process apparatus unit control section 32. Both the carry-in/carry-out mechanism 31 and a process apparatus unit control section 32 control a series of processes on the basis of received recipe information. As a result, manufacture of many kinds of articles in small amounts can be effected easily, and production efficiency is improved.



BEST AVAILABLE COPY